

ELIZADE UNIVERSITY, ILARA-MOKIN, ONDO STATE, NIGERIA

DEPARTMENT OF AUTOMOTIVE ENGINEERING

FIRST SEMESTER EXAMINATIONS

2019/2020 ACADEMIC SESSION

COURSE: ATE 305 – Micro-Electro-Mechanical-Systems (3 Units)

CLASS: 300 Level Automotive Engineering

TIME ALLOWED: 2 ½ Hours

INSTRUCTIONS: Answer any **FIVE** questions



HOD'S SIGNATURE

Date: February, 2020

Question 1 (General)

<u> vacetion i (General)</u>	
a. Briefly explain the MCNC MUMPs and MOSIS	[3 Marks]
b. With sketches, differentiate between NPN and PNP transistors	-
C. List any two wafer manufact.	[3 Marks]
c. List any two wafer manufacturing methods	[2 Marks]
d. List the steps required in LIGA micromachining	[3 Marks]
e. What is the function of Micro-positioners ?	-
of the familiary of twice oppositioners?	[1 Mark]
Question 2 (IC CAD tools to design MEMS structures using MCNC MUMPs service	رم '
a. What are MEMS CAD Tools?	
	[2 Marks]
b. List any four advantages of MUMPs and MOSIS	[4 Marks]
c. Sketch and explain the MEMS design flow chart	- 1
d What is the full maning fell of the	[4 Marks]
d. What is the full meaning of the following acronyms: (i) VLSI (ii) ULSI?	[2 Marks]
Question 3 (Basic IC and Wafer Production Techniques)	[2 Walks]
2 List the basic steps required in the ward of the same	
a. List the basic steps required in the production of Integrated Circuit (IC)	[2 ½ Marks]
b. Sketch, list and briefly explain Czochralski Method in relation to fig. Q3(b)	-
relation to fig. Q3(b)	[4 ½ Marks]

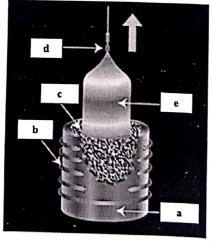


Fig. Q3(b)

[2 Marks]

- c. What is the essence of initial and final wafer tests in IC fabrication?
- d. What is the full meaning of the following acronyms?

[3 Marks]

(i) DRIE (ii) RIE (iii) LIGA

Question 4 (Micro-actuators and Micro-sensors)

[3 Marks]

a. Differentiate between Micro-actuators and Microsensors?

[1 1/2 Marks]

- b. Why are MEMS used for Sensors?
- c. Give any three examples of non-electrical physical or chemical quantity that are being converted into electrical signal by microsensors.
- d. Briefly explain the following:

[6 Marks]

(i) Micro-motor (ii) Micro-gripper (iii) Micro accelerometer

Question 5 (Basic IC Manufacturing Processes)

a. What is **Photolithography**?

[2 Marks]

b. Sketch, label and briefly explain photolithography process in relation to fig. Q3(b) [5 Marks]

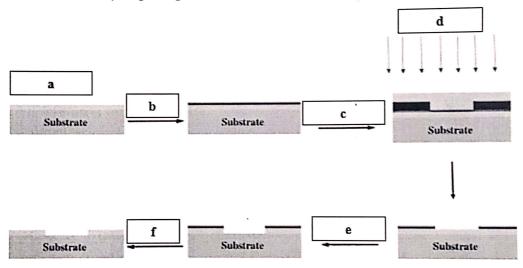


Fig. Q3(b)

c. What is the function of HMDS in photolithography?

[2 Marks]

d. What is the full meaning of the following acronyms in relation to Micro-Electro-Mechanical-System: (i) PMMA (ii) HMDS (iii) MST? [3 Marks]

Question 6 (Micro-electromechanical systems fabrications)

a. (i) What are MEMS? (ii) List any three Automotive applications of MEMS?

[3 Marks]

b. List the three MEMS fabrication methods, explain briefly any one.

[4 Marks]

c. In relation to MEMS fabrication, differentiate between the following: (i) Dry and Wet Etching (ii) Isotropic and Anisotropic Etchants [5 Marks]

Question 7 (Electronics Devices Fundamentals)

- a. Define the following terms: (i) Integrated circuit (ii) Semiconductor (iii) Emitter (iv) Collector. [4 Marks]
- b. Differentiate between active and passive components

[3 Marks]

c. What is the difference between 'VLSI' and 'ULSI'?

[3 Marks]

d. Determine the value of the resistor in the 4-colour band resistor shown in fig. Q7 (b).

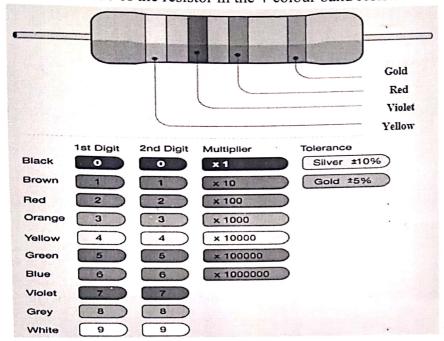


fig. Q7 (b) [2 Marks]